

EIKOH PATENT OFFICE

PATENT, DESIGN
AND TRADEMARK

ARK MORI BLDG, 13F
12-32 AKASAKA 1-CHOME
MINATO-KU, TOKYO 107-6013, JAPAN

FAX: +81-3-5561-3995
+81-3-5561-3996
TEL: +81-3-5561-3990
E-mail:eikoh@eikoh-patent.gr.jp

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The International Bureau of WIPO
PCT Operations Department
34, Chemin des Colombettes
1211 GENEVA 20
SWITZERLAND

Facsimile No. (41-22)338-8270

Amendment of the claims under Article 19(1) (Rule 46)

International Application No. : PCT/JP2005/010790

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Applicant : MATSUSHITA ELECTRIC INDUSTRIAL CO., LTD. et al
1006, Oaza Kadoma, Kadoma-shi, Osaka 571-8501 JAPAN

Agent : TAKAMATSU Takeshi, ICHIKAWA Toshimitsu,
HASHIMOTO Kimihide

Agent's File reference : P05328800

Dear Sir,

The Applicant, who received the International Search Report relating to the above-identified International Application transmitted on 04.10.2005, hereby files amendment under Article 19(1) as in the attached sheets.

We hereby would like to amend the claim 1.

The claims 2-27 are retained unchanged.

Very truly yours,

Takamatsu Takeshi
TAKAMATSU Takeshi

Attachment:

(1) Amendment under Article 19(1) 1 sheet

CLAIMS

1. (Amended) An electromechanical signal selection device comprising:

5 a micro-vibrator which can be excited by an input signal;
and

a post for retaining the micro-vibrator,
wherein the micro-vibrator can generate a change in
physical property due to excitation so as to select a selected
10 signal.

2. The electromechanical signal selection device according
to claim 1, wherein the micro-vibrator comprises a material
whose physical property is changed in accordance with a
15 structural change.

3. The electromechanical signal selection device according
to claim 1 or 2, wherein the physical property is an electric
conduction characteristic.

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4. The electromechanical signal selection device according
to claim 1, wherein the micro-vibrator is retained by an
electrode placed on the post.

25 5. The electromechanical signal selection device according

to claim 4, wherein a bonded surface between the electrode and the micro-vibrator is located at a distance from the post.

6. The electromechanical signal selection device according
5 to claim 1, wherein the post comprises a structure having lower
rigidity than that of the micro-vibrator.

7. The electromechanical signal selection device according
to claim 1, wherein the micro-vibrator comprises a multilayer
10 structure of at least two layers including a material layer
generating the change in physical property and a conductor layer.

8. The electromechanical signal selection device according
to claim 7,

15 wherein the conductor is formed to be linear, and
wherein the material layer generating the change in
physical property is formed around the linear conductor layer.

9. The electromechanical signal selection device according
20 to claim 7, wherein the material layer generating the change
in physical property is formed on the side where an electric
field of a signal is concentrated.